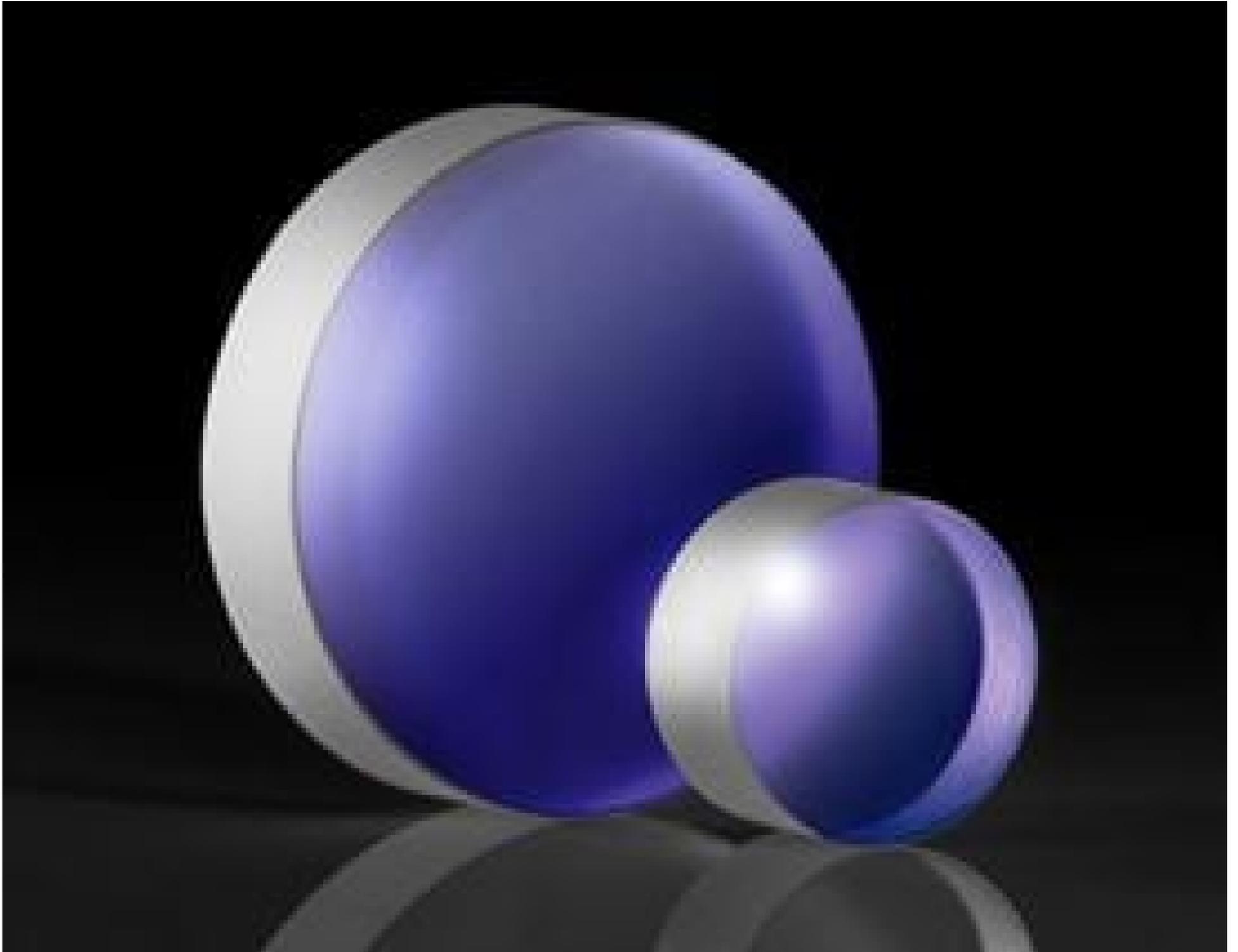


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## 50.8mm Dia., 9.54mm Thick, Fused Silica 400nm Ti:Sapphire Mirror, 0-45 Deg AOI



Stock #28-991 **4 In Stock**

MRP ₹32,285

**i** Price inclusive of all taxes

**ADD TO CART**

Volume Pricing	
Qty 1-5	₹32,285 each
Qty 6-25	₹25,828 each
Need More?	<a href="#">Request Quote</a>

### Product Downloads

### General

Ti:Sapphire Laser Mirror **Type:**

### Physical & Mechanical Properties

9.54 ±0.20 **Thickness (mm):**

45.72 **Clear Aperture CA (mm):**

**Diameter (mm):**

50.80 +0.00/-0.10

Parallelism (arcmin):

<3

Edges:

Fine Ground

## Optical Properties

Substrate:

Fused Silica (Corning 7980)

Surface Quality:

10-5

Angle of Incidence (°):

0-45

Coating:

Laser Mirror (400nm)

Design Wavelength DWL (nm):

400

Wavelength Range (nm):

390 - 410

Surface Flatness (P-V):

$\lambda/10$

Coating Specification:

R<sub>abs</sub> S & P >99.80% @ 400nm @ 0-45° AOI

## Regulatory Compliance

Certificate of Conformance:

[View](#)

Country of Origin:

United States

Imported By:

Edmund Optics India Private Limited  
267, Greystone Building, Second Floor,  
6th Cross Rd, Binnamangala,  
Stage 1, Indiranagar, Bengaluru,  
Karnataka, India 560038  
Phone: +91- 80-6845 0000

## Product Details

- >99.8% Reflectivity at Ti:Sapphire Fundamental and Harmonic Frequencies
- 10-5 Surface Quality for Reduced Scatter in Laser Applications
- High Laser Damage Threshold

TECHSPEC® Ti:Sapphire Laser Line Mirrors provide >99.8% reflectivity for Ti:Sapphire laser fundamental and harmonic frequencies at both a 45° angle of incidence (AOI) and 0-45° AOI. These laser mirrors are designed with a fused silica substrate for excellent thermal stability and are coated for 800nm, 400nm, or 266nm which are the fundamental, second harmonic, and third harmonic respectively. To minimize scattering effects, these mirrors feature a high 10-5 surface quality and  $\lambda/10$  surface flatness. TECHSPEC® Ti:Sapphire Laser Line Mirrors are ideal for a range of Ti:Sapphire laser applications such as multiphoton imaging, ultrafast spectroscopy, and cold micromachining.